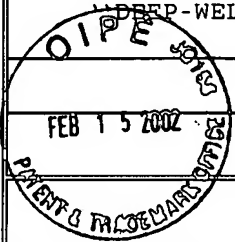


U.S. Department of Commerce, Patent and Trademark Office	Serial No.: 10/027,882
	Filing Date: 12/21/01
INFORMATION DISCLOSURE STATEMENT BY APPLICANT	Inventors: Vlad J. Novotny
DEEP-WELL LITHOGRAPHY PROCESS FOR FORMING MICRO-ELECTRO-MECHANICAL STRUCTURES"	Group Art Unit: Unknown 1765
	Examiner Name: Unknown S. Ahmed
	Attorney Docket No.: AO-001-2D



U.S. Patent Documents

*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date, If Appropriate
AA						
AB						

Foreign Patent Documents

							Translation
	Document Number	Date	Country	Class	Subclass	Yes	No
AC							

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

SA	AD	D.J. Bishop Presentation, "Silicon Micromachines for Lightwave Networks: Can Little Machines Make it Big?" Lucent Technologies, Bell Labs Innovations. 83 pages. February 1999.
	AE	
	AF	
	AG	
	AH	
	AI	

RECEIVED
FEB 25 2002
TC 2800 MAIL ROOM

Examiner Shamim Ahmed

Date Considered 7/10/03

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.

U.S. Department of Commerce, Patent and Trademark Office	Serial No.: Unknown
	Filing Date: 12/21/01
INFORMATION DISCLOSURE STATEMENT BY APPLICANT	Inventor: Vlad J. Novotny
"Deep-Well Lithography Process for Forming Micro-Electro-Mechanical Structures"	Group Art Unit: Unknown
	Examiner Name: Unknown
Express Mail Receipt No.: EK916849783US	Attorney Docket No.: AO-001-2D

U.S. Patent Documents

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date, If Appropriate
SA	AA	6,301,403 B1	10/09/01	Heanue et al.	385	18	
SA	AB	6,253,001 B1	06/26/01	Storrs T. Hoen	385	17	
SA	AC	6,028,689	02/22/00	Michalicek et al.	359	224	
SA	AD	5,872,880	02/16/99	Ronald S. Maynard	385	88	
SA	AE	6,283,601 B1	09/04/01	Hagelin et al.	359	871	

Foreign Patent Documents

							Translation	
		Document Number	Date	Country	Class	Subclass	Yes	No
	AF							

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

SA	AG	"ROUTING PACKETS WITH LIGHT," Daniel J. Blumenthal. Scientific American, pages 96-99. January 2001.						
SA	AH	"Construction and performance of a 576x576 single-stage OXC," Herzel Laor. LEOS, San Francisco, California, 3 pages. November 8, 1999.						
NO Date SA	AI	"Application of micro- and nanotechnologies for the fabrication of optical devices," Wolfgang Ehrfeld and Hans-Dieter Bauer. SPIE Vol. 3276, page 2 and pages 4-14.						
SA	AJ	"PERFORMANCE OF A 576x576 OPTICAL CROSS CONNECT," Laor, et al. NFOEC, Chicago, Illinois, pages 1-5. September 26, 1999.						
NO Date SA	AK	"Control and shape design of an electrically-damped comb drive for digital switches," Yijian Chen. Proceedings of SPIE Vol. 4178, 2000. Pages 387-394.						

Examiner

Shamim Ahmed

Date Considered

7/10/03

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.

U.S. PTO
10/02/7882
12/21/01

U.S. Department of Commerce, Patent and Trademark Office						Serial No.: Unknown		
						Filing Date: 12/2/01		
INFORMATION DISCLOSURE STATEMENT BY APPLICANT						Inventor: Vlad J. Novotny		
"Deep-Well Lithography Process for Forming Micro-Electro-Mechanical Structures"						Group Art Unit: Unknown		
						Examiner Name: Unknown		
Express Mail Receipt No. EK916849783US						Attorney Docket No.: AO-001-2D		
U.S. Patent Documents								
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date, If Appropriate	
	AL							
Foreign Patent Documents								
							Translation	
		Document Number	Date	Country	Class	Subclass	Yes	No
	AM							
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)								
SA	AN	"THE RISE OF OPTICAL SWITCHING," David J. Bishop et al. Scientific American, pages 88-94. January 2001.						
NO Date	AO	"A LARGE-DEFLECTION ELECTROSTATIC ACTUATOR FOR OPTICAL SWITCHING APPLICATIONS," John D. Grade, Hal Jerman and Thomas W. Kenny. Presented at Hilton Head, 2000. 4 pages.						
	AP	"FLIP CHIP CHALLENGES," Steve Bezuk, PH.D. General Manager, Applied Technology Development and Flip Chip Kyocera America, Inc. First published in HDI Magazine, February 2000. 6 pages.						
NO Date	AQ	"MEMS Feedback Control Using Through-Wafer Optical Device Monitoring," J.M. Dawson, et al. Proceedings of SPIE Vol. 4178, 2000. Pages 221-227.						
SA	AR	"A FLAT HIGH-FREQUENCY SCANNING MICROMIRROR," Robert A. Conant, et al. 2000 Solid-State Sensor & Act Workshop, Hilton Head, S.C., June 4-8, 2000.						
SA	AS	"The Surface/Bulk Micromachining (SBM) Process: A New Method for Fabricating Released MEMS in Single Crystal Silicon," Sangwoo Lee, et al. Journal of Microelectromechanical Systems, Vol. 8, No. 4, December 1999. Pages 409-416.						
NO Date SA	AT	"MEMS actuators for silicon micro-optical elements," Norman C. Tien and Daniel T. McCormick. Proceedings of SPIE Vol. 4178, 2000. 256-267.						
Examiner				Date Considered				
Shamim Ahmed				7/10/03				
<p>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.</p>								

U.S. Department of Commerce, Patent and Trademark Office						Serial No.: Unknown		
						Filing Date: 12/21/01		
INFORMATION DISCLOSURE STATEMENT BY APPLICANT						Inventor: Vlad J. Novotny		
"Deep-Well Lithography Process for Forming Micro-Electro-Mechanical Structures"						Group Art Unit: Unknown		
						Examiner Name: Unknown		
Express Mail Receipt No. EK916849783US						Attorney Docket No.: AO-001-2D		
U.S. Patent Documents								
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date, If Appropriate	
	AU							
Foreign Patent Documents								
							Translation	
		Document Number	Date	Country	Class	Subclass	Yes	No
	AV							
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)								
SA	AW	"Lightweight, Optically Flat Micromirrors for Fast Beam Steering," Jocelyn T. Nee, et al. Presented at IEEE/LEOS Optical MEMS 2000 Conference, August 21-4, 2000, Kauai, Hawaii, USA. 2 pages.						
SA	AX	"Optical MEMS for Optical Communications - Trends and Developments," Veljko Milanovic. Adriatic Research Institute. Pages 2-6. Downloaded December 20, 2001.						
	AY							
	AZ							
	BA							
	BB							
Examiner Shamim Ahmed				Date Considered 7/10/03				
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.								

U.S. Department of Commerce, Patent and Trademark Office	Serial No.: Unknown
	Filing Date: 12/21/01
INFORMATION DISCLOSURE STATEMENT BY APPLICANT	Inventor: Vlad J. Novotny
"Deep-Well Lithography Process for Forming Micro-Electro-Mechanical Structures"	Group Art Unit: Unknown
	Examiner Name: Unknown
Express Mail Receipt No. EK916849783US	Attorney Docket No.: AO-001-2D

U.S. Patent Documents

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date, If Appropriate
SA	BC	6,252,466 B1	06/26/01	J. Patrick Kawamura	331	25	
SA		6,097,859	08/01/00	Solgaard et al.	385	17	

Foreign Patent Documents

							Translation	
		Document Number	Date	Country	Class	Subclass	Yes	No
	BD							

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

No date ↓	BE	Topical Review "The future of MEMS in telecommunications networks," James A. Walker. J. Micromech, Microeng 10(2000)R1-R7. Printed in the UK.
	BF	D.J. Bishop Presentation, "Silicon Micromachines for Lightwave Networks: Can Little Machines Make it Big?" Lucent Technologies, Bell Labs Innovations. 83 pages. Date unknown.
	BG	
	BH	
	BI	
	BJ	

Examiner

Shamim Ahmed

Date Considered

7/10/03

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.



U.S. Department of Commerce, Patent and Trademark Office	Serial No.: 10/027,882
	Filing Date: 12/21/01
SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT BY APPLICANT	Inventor: Vlad J. Novotny
"Deep-Well Lithography Process for Forming Micro-Electro-Mechanical Structures"	Group Art Unit: 2874
	Examiner Name: Unknown
	Attorney Docket No.: AO-001-2D

U.S. Patent Documents

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date, If Appropriate
SA	AA	5,724,123	03/03/98	Tanaka	356	5.01	
SA	AB	6,320,993B1	11/20/01	Laor	385	16	

Foreign Patent Documents

							Translation	
		Document Number	Date	Country	Class	Subclass	Yes	No
	AC							

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

SA	AD	"Silicon micromachines for lightwave networks: the little machines that will make it big," by David Bishop. December 2000. SPIE's Optics & Information Systems. 8 pages.
	AE	
	AF	
	AG	
	AH	
	AI	

Examiner <i>Shamim Ahmed</i>	Date Considered <i>7/10/03</i>
------------------------------	--------------------------------

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.



U.S. Department of Commerce, Patent and Trademark Office	Serial No.: 10/027,882
	Filing Date: 12/21/2001
SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT BY APPLICANT	Inventor: Vlad J. Novotny
	Group Art Unit: Unknown
"DEEP-WELL LITHOGRAPHY PROCESS FOR FORMING MICRO-ELECTRO-MECHANICAL STRUCTURES"	Examiner Name: Unknown
	Attorney Docket No.: AO-001-2D

U.S. Patent Documents

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date, If Appropriate
	A						
	B						
	C						
	D						
	E						

RECEIVED
JUN 18 2003
TC 1700RECEIVED
JUN 12 2003
MAIL ROOM

Foreign Patent Documents

		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
	F							

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

SA	G	"Multi-Layer, Self-Aligned Vertical Combedrive Electrostatic Actuators and Fabrication Methods." Inventors: Behrang Behin and Satinderpall Pannu. Publication No.: US 2002/0005976 A1. Publication Date: January 17, 2002. Application No.: 09/810,333, filed March 14, 2001.
	H	
	I	
	J	

Examiner

Shamim Ahmed

Date Considered

7/10/03

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.